

GaBiAs epitaxial layers for terahertz optoelectronic applications

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- Introduction. THz optoelectronic devices.
- GaBiAs: technology and main physical characteristics.
- THz time-domain system based on GaBiAs components.
- THz burst generation by optical mixing.
- Conclusions. Other possible ultrafast applications of GaBiAs components.



Acknowledgements

Vilnius:

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Prof. S. Marcinkevičius

Berkeley:

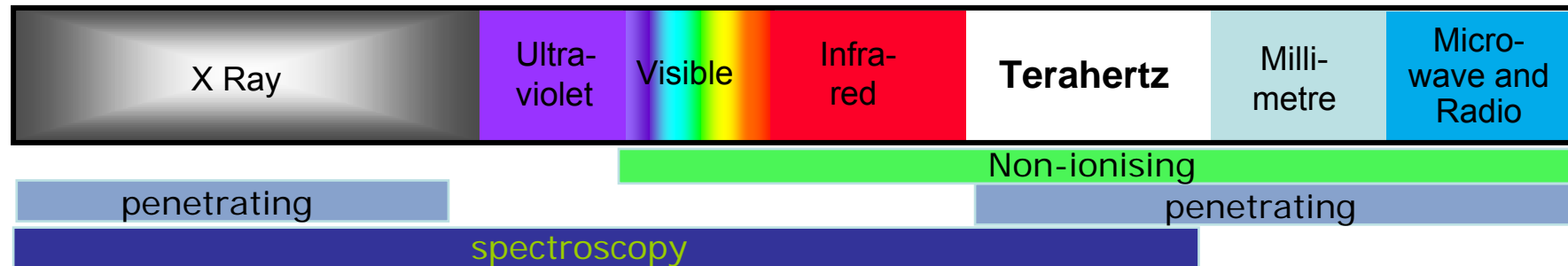
Prof. W. Walukiewicz, Dr. K.M. Yu.

Lithuanian Science & Study Foundation.

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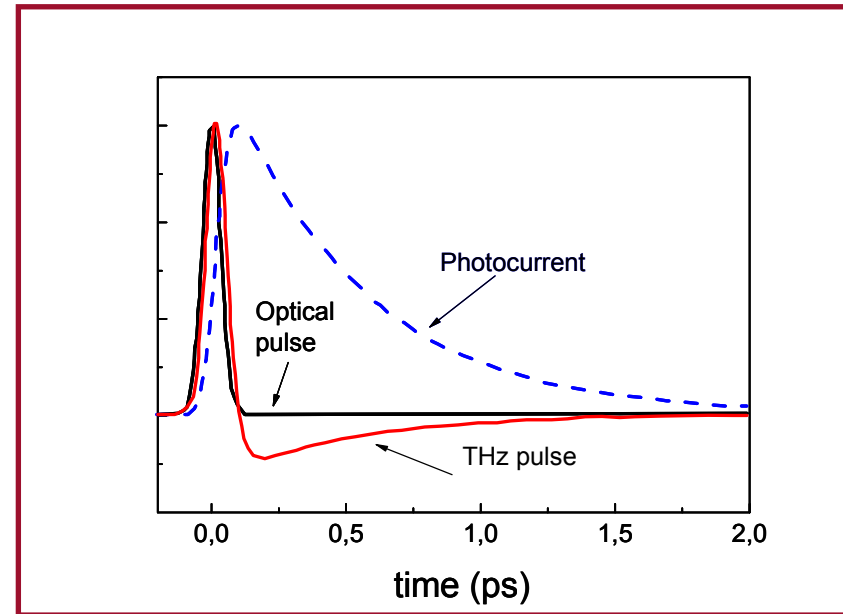
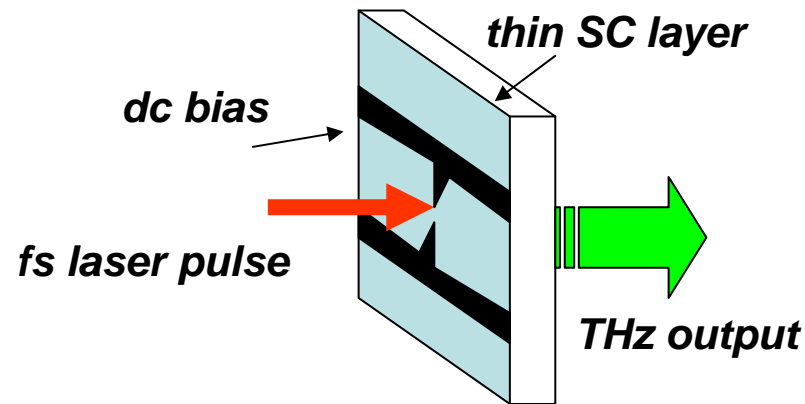
THz frequency range



- *Key properties:*
 - *Penetrates clothing, leather, paper, plastics, packaging materials.*
 - *Materials identification using characteristic Terahertz spectra.*
 - *3-D imaging capability.*
 - *Non-ionizing - no damage to body or cells*
 - *Short wavelength – high resolution*



THz pulse emission



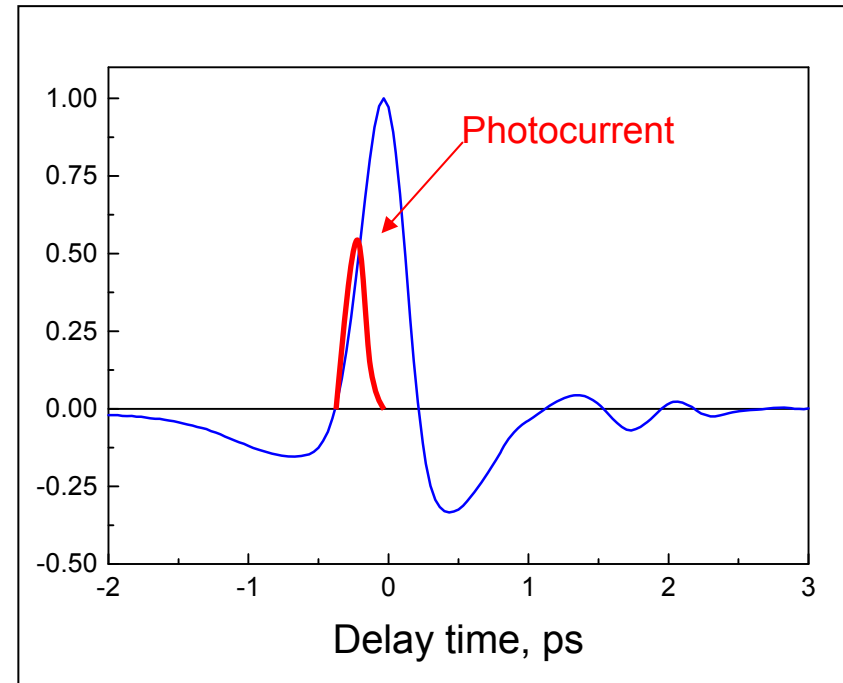
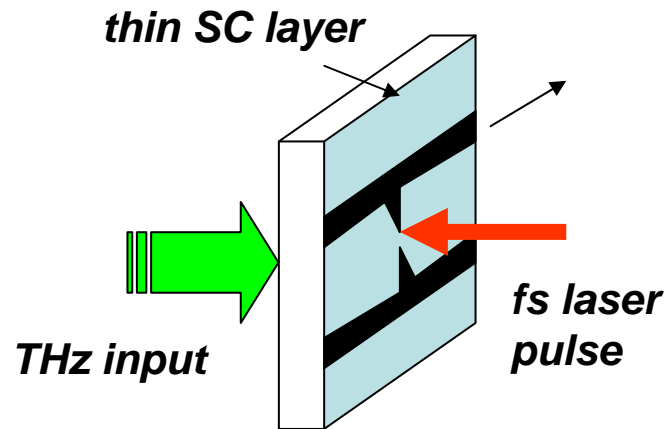
- Biased photoconductor made from a material sensitive in the fs laser wavelength range;
- Contact metallization has the shape of a Hertzian dipole type antenna;
- THz pulse is emitted into free space.

$$j_{em}(t) = P(t) \otimes [n_{em}(t)qv(t)]$$

$$E_{THz}(t) \propto \frac{dj_{em}(t)}{dt}$$



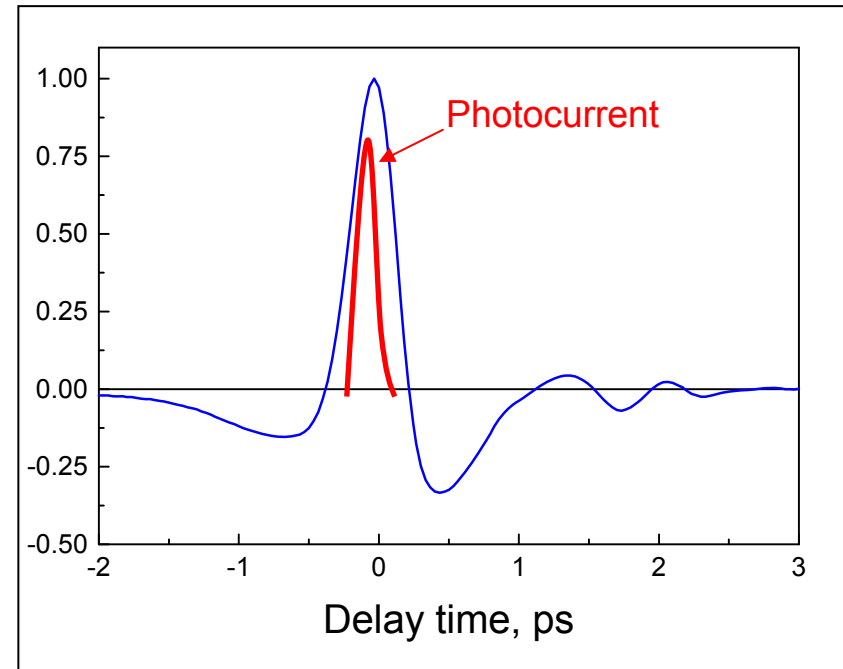
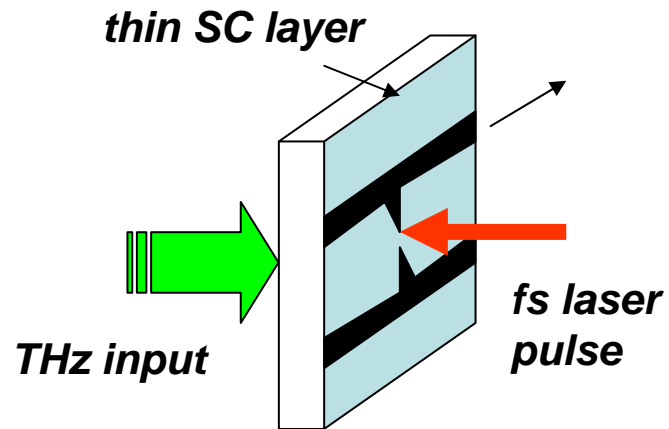
THz pulse detection



- *Electro-optical and photoconductive detection;*
- *Photoconductor made from material with ultrashort carrier lifetime is biased by the incoming THz pulse;*
- *By illuminating it at different time delays, different parts of THz pulse are sampled;*



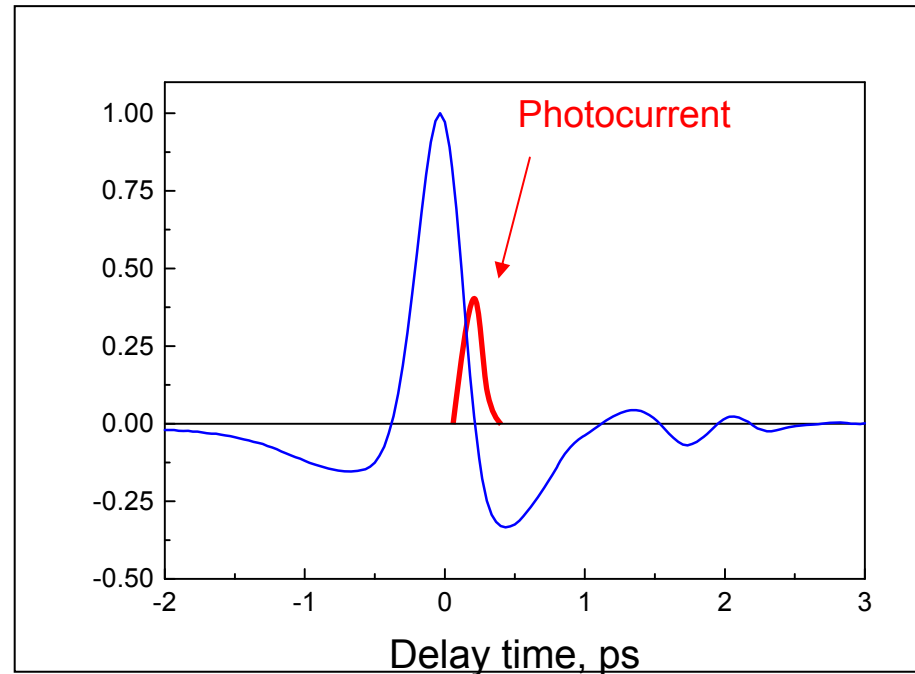
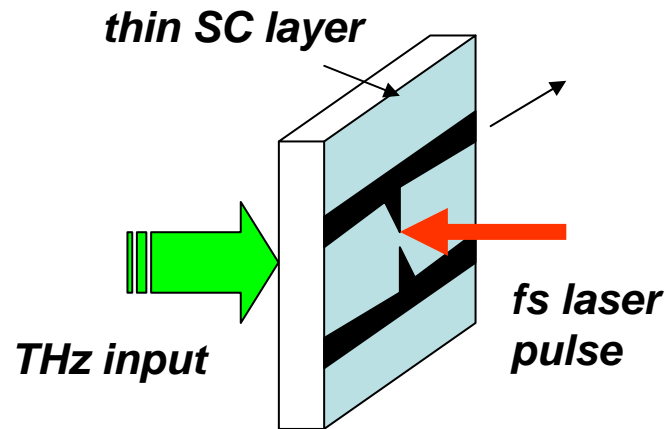
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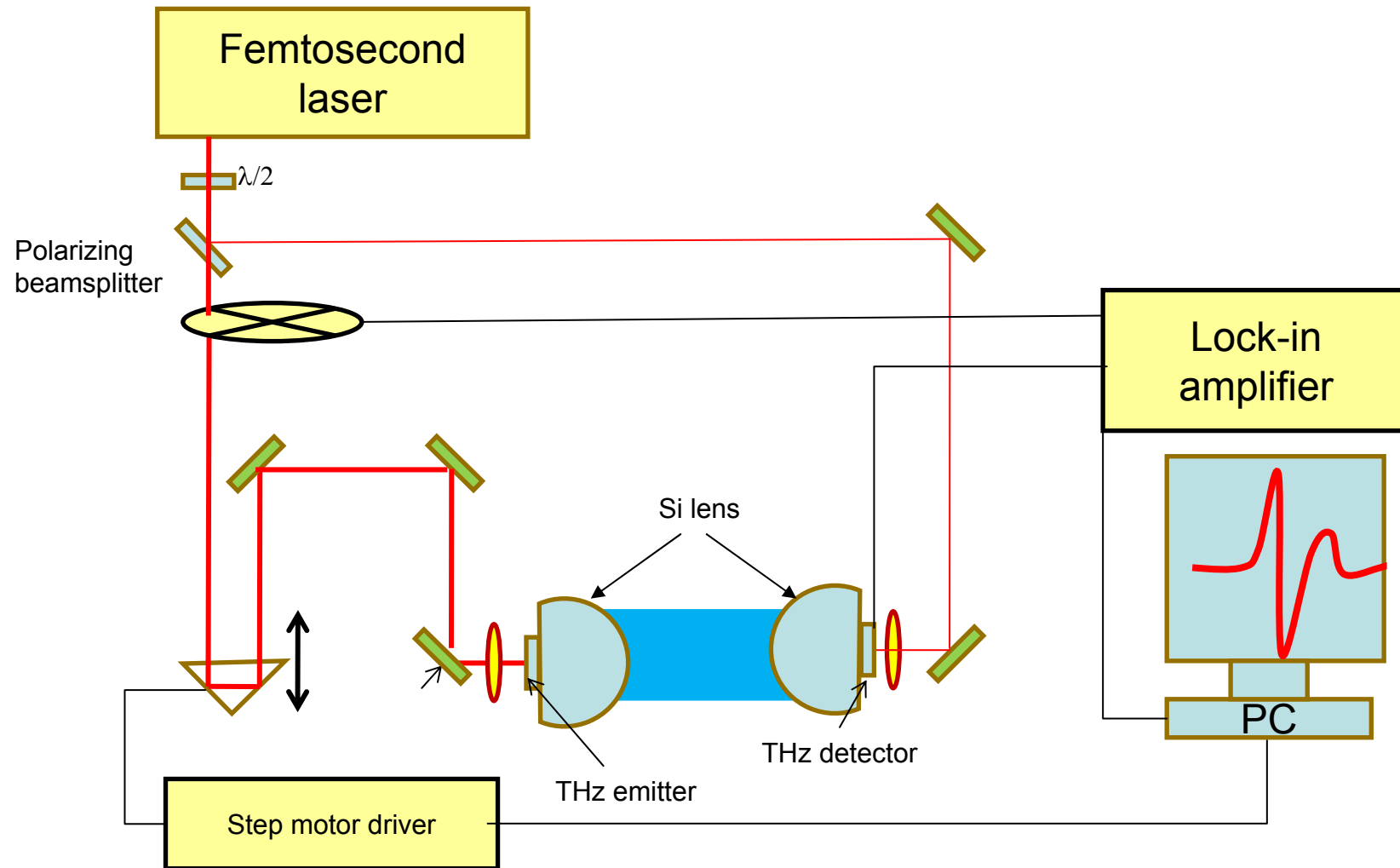


THz pulse detection



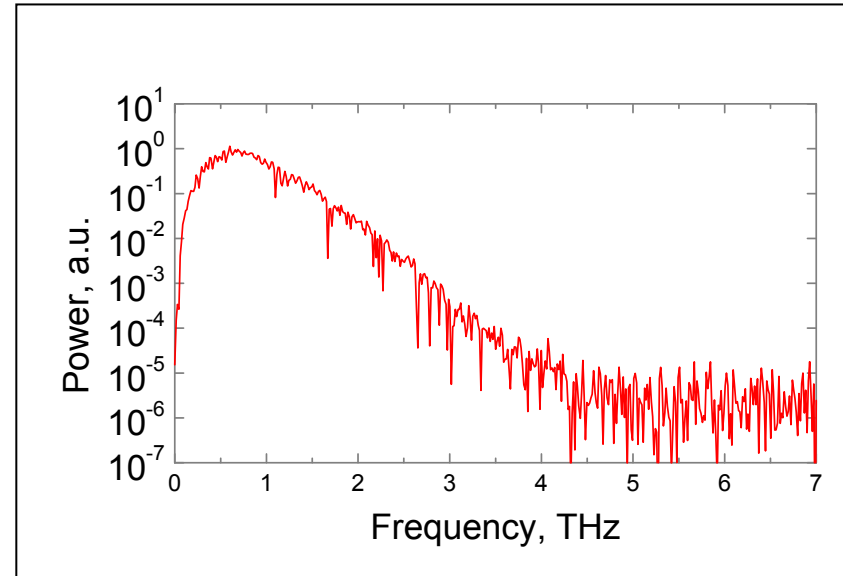
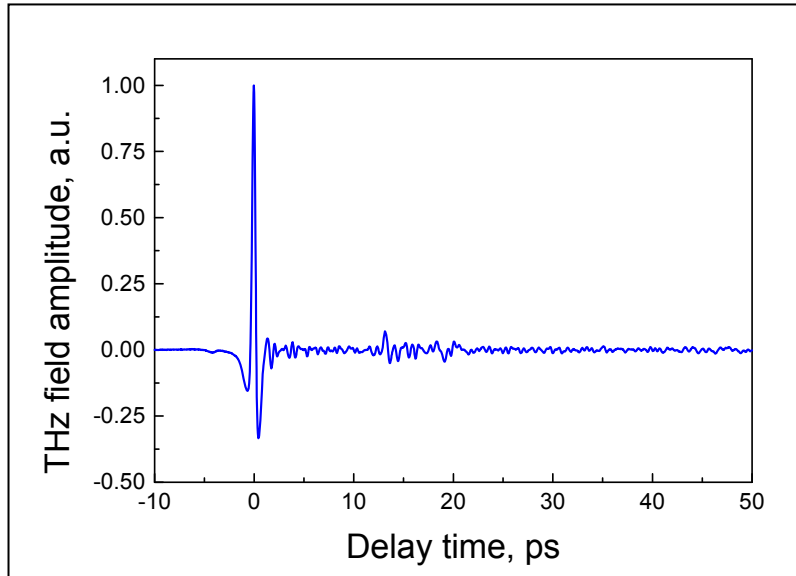
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- *Photoconductor made from material with ultrashort carrier lifetime is biased by the incoming THz pulse;*
- *By illuminating it at different time delays, different parts of THz pulse are sampled;*
- *Critical material parameter – carrier lifetime.*

THz TDS set-up





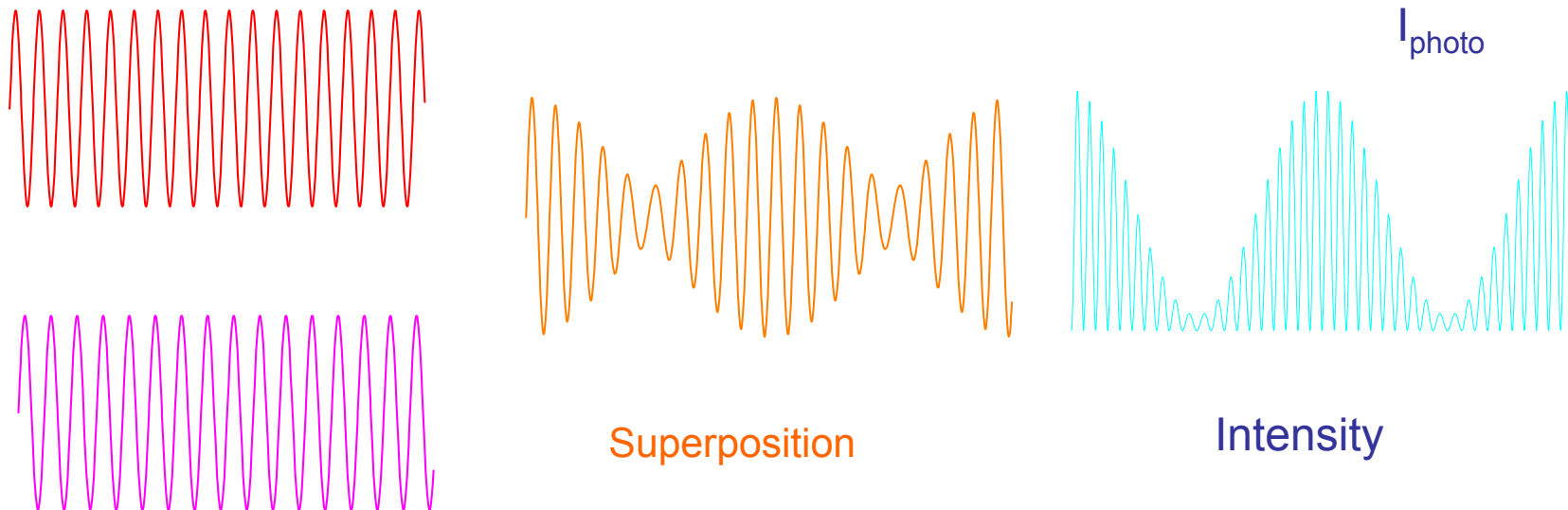
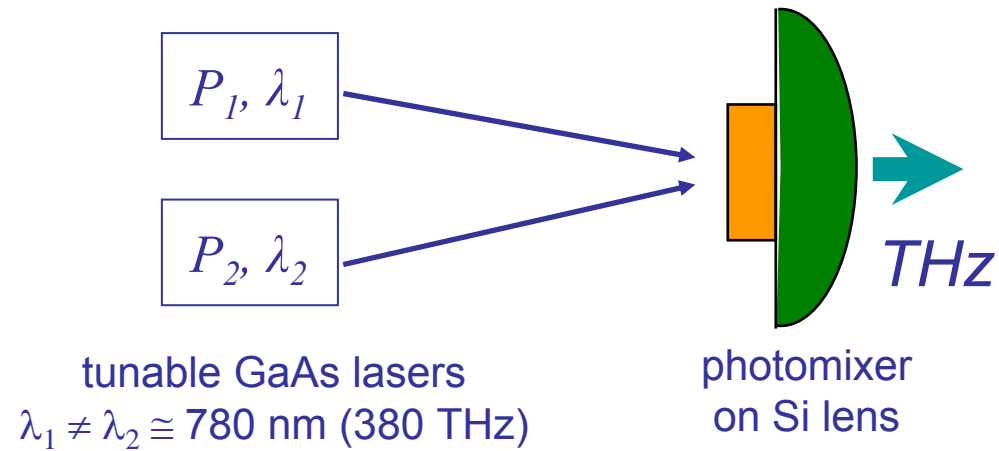
Terahertz pulses



- *Ultrafast electrical transients generated using femtosecond laser pulses;*
- *Their Fast-Fourier transform spectrum is shown on the right;*
- *Signal-to-noise ratios better than 60 dB easily achievable;*
- *Coherent detection – both amplitude and phase of different frequency components can be measured.*



THz optical mixers





Important material parameters

Energy bandgap – semiconductor should be photosensitive at the laser wavelength.

- **THz pulse emitters:** dark resistance, electron mobility, breakdown field, lifetime (shorter than the laser pulse repetition period).
- **THz pulse detectors:** electron trapping time, electron mobility, dark resistance.
- **Optical mixers:** electron and hole trapping times, dark resistance.

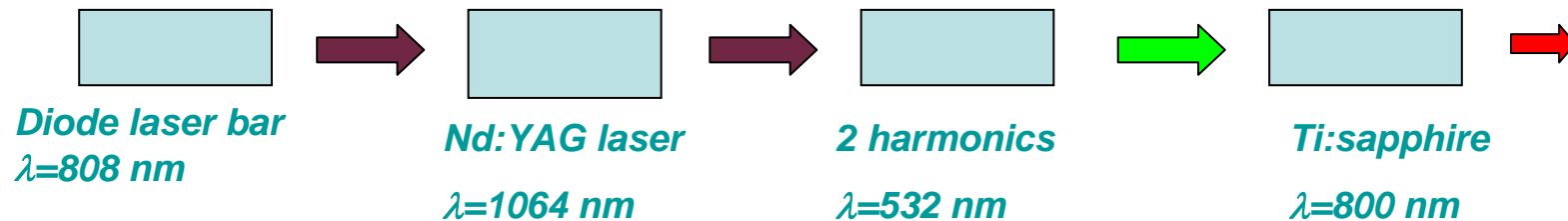
TDS with Ti:sapphire laser

Advantages:

- * *Mature laser technology (700-800 nm);*
- * *LTG GaAs – material sub-ps lifetimes, high resistivity, electron mobility, and with energy bandgap matching the laser photon energy.*

Disadvantages:

- * *Complex optical pumping scheme;*
- * *Cannot be made much smaller and cheaper.*





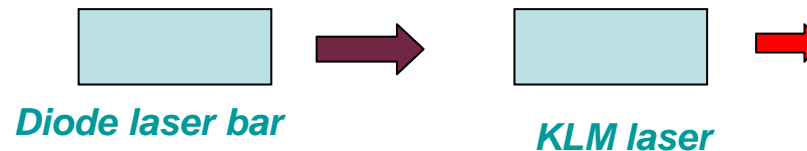
Infrared fs lasers

Advantages:

- *1 μm or 1.55 μm wavelength range solid-state or fiber laser are already commercially available;*
- *Directly pumped by diode laser bars;*
- *Compact, efficient, cheaper.*

Disadvantages:

- *Semiconductor material similar to LTG GaAs but sensitive to longer wavelengths required;*
- *Longer wavelength means narrower energy bandgap and smaller dark resistivities.*





Choice of materials

$\text{In}_x\text{Ga}_{1-x}\text{As}$:

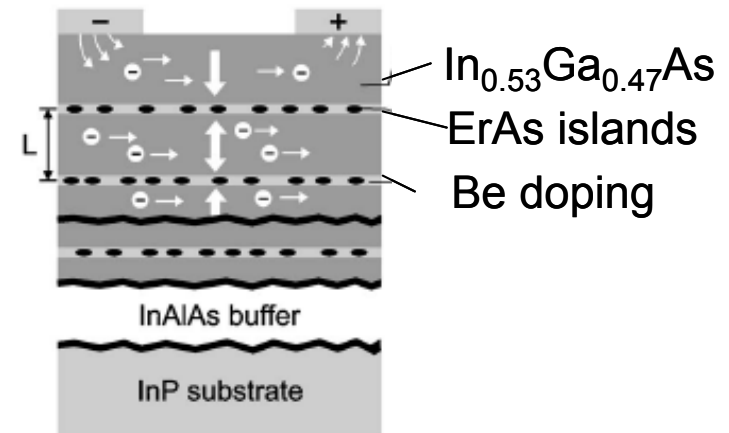
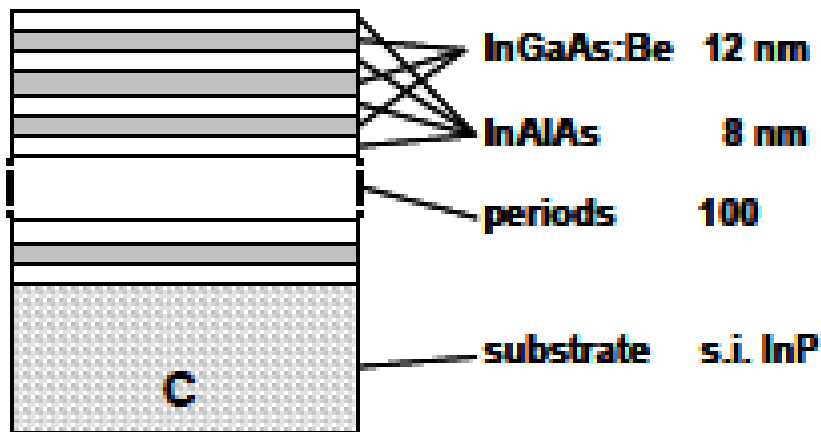
- LTG (at 200°C) on GaAs. $x=0.25$ ($\lambda\sim 1.05\ \mu\text{m}$); dark resistivity $8\cdot 10^3\ \Omega\cdot\text{cm}$, lifetime $\sim 7\ \text{ps}$.
- LTG (at 180°C) on InP substrates. $x=0.53$ ($\lambda\sim 1.5\ \mu\text{m}$): free electron density $> 10^{18}\ \text{cm}^{-3}$, lifetime $\sim 2\ \text{ps}$;
- LTG, Be-doped. $x=0.53$ ($\lambda\sim 1.5\ \mu\text{m}$): free electron density $5\cdot 10^{16}\ \text{cm}^{-3}$, lifetime $\sim 2\ \text{ps}$;
- heavy ion implanted (Au^+ , Br^+ , or Fe^+): dark resistivity $< 10\ \Omega\cdot\text{cm}$, electron lifetimes $0.5\div 2\ \text{ps}$.

$\text{GaSb}_x\text{As}_{1-x}$:

- LTG (at 170°C) on GaAs substrates. $x=0.4$ ($\lambda\sim 1.4\ \mu\text{m}$): dark resistivity $\sim 10^4\ \Omega\cdot\text{cm}$.



Layered structures



InGaAs – photoconductive layer;

Be- doping – for compensation of the residual donors;

InAlAs – LTG electron trapping layer.

B. Sartorius, Opt.Expr., 16, 9565 (2008)

InGaAs – photoconductive layer;

Be- doping – for compensation of the residual donors;

ErAs –electron trapping nanoclusters.

F. Ospald, APL., 92, 131117 (2008)

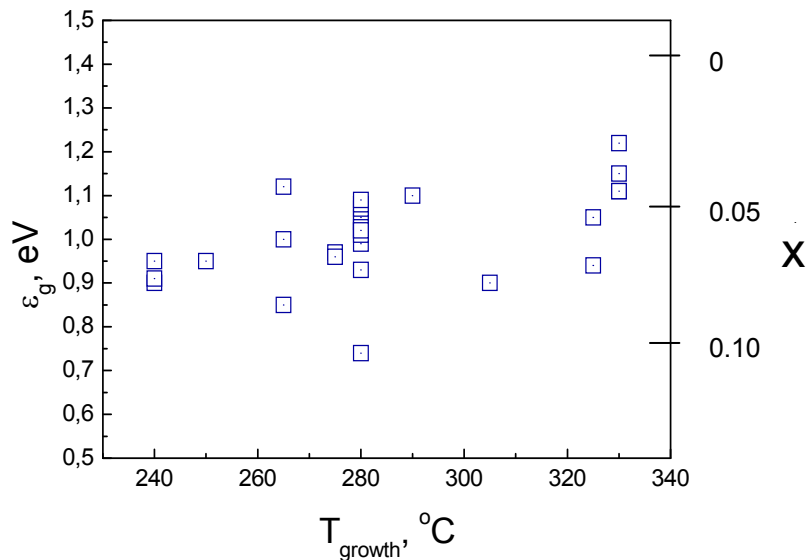


Our way to GaBiAs

- ❖ 1995 – 2003. Low-temperature MBE grown GaAs; heavy ion implanted GaAs for ultrafast optoelectronic applications;
- ❖ Search of a short-lifetime material with a low mismatch to GaAs.
- ❖ 2003. Papers from T. Tiedje and Kyoto groups on $\text{GaBi}_x\text{As}_{1-x}$ grown by MBE. $x=3.1\%$ (S.Tixier et.al, APL) and $x=4.5\%$ (M. Yoshimoto et.al., Jpn.J. Appl. Phys.). Growth temperatures were 380°C and 350°C , respectively.
- ❖ 2005. Starting MBE growth at even lower substrate temperatures $240\text{-}330^\circ\text{C}$.
- ❖



Growth technology

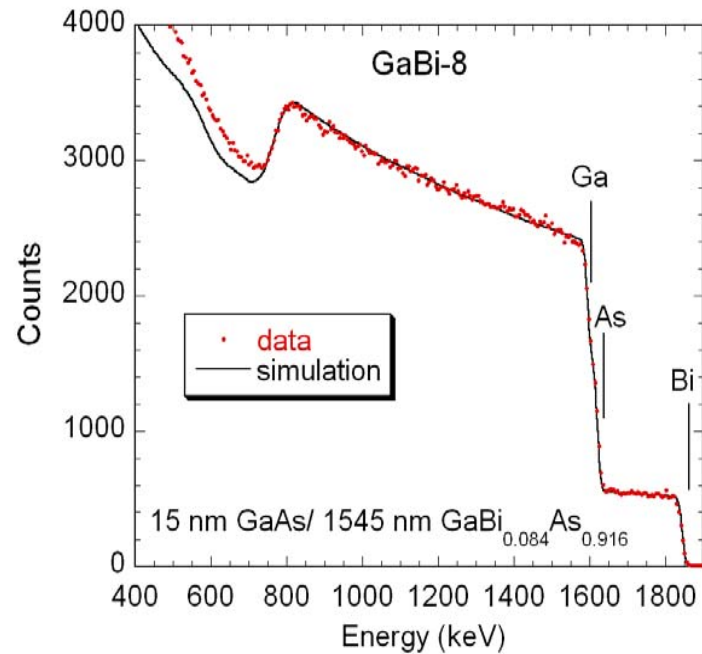


Bandgap versus the growth temperature for 30 GaBiAs growth runs.

- ❖ *Soviet –made MBE machine (ШТАТ).*
- ❖ *As₄ source.*
- ❖ *x=5 % (K. Bertulis et.al. APL,2006).*
- ❖ *x=8.5% (V. Pacebutas et.al., Sem.Sc.Technol., 2007).*
- ❖ *x=11 % (V. Pacebutas et.al., J. Mater,Sc., 2008)*

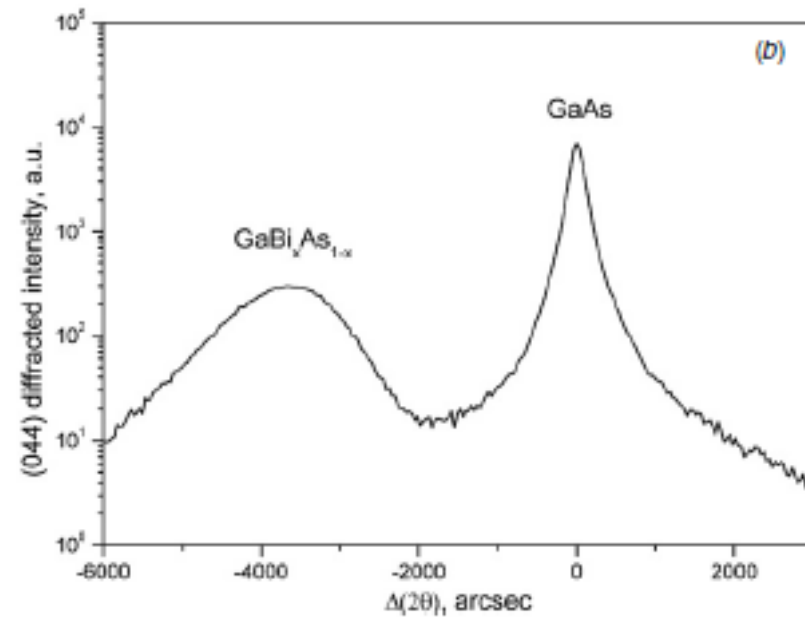


Alloy composition



Rutherford Back-Scattering.

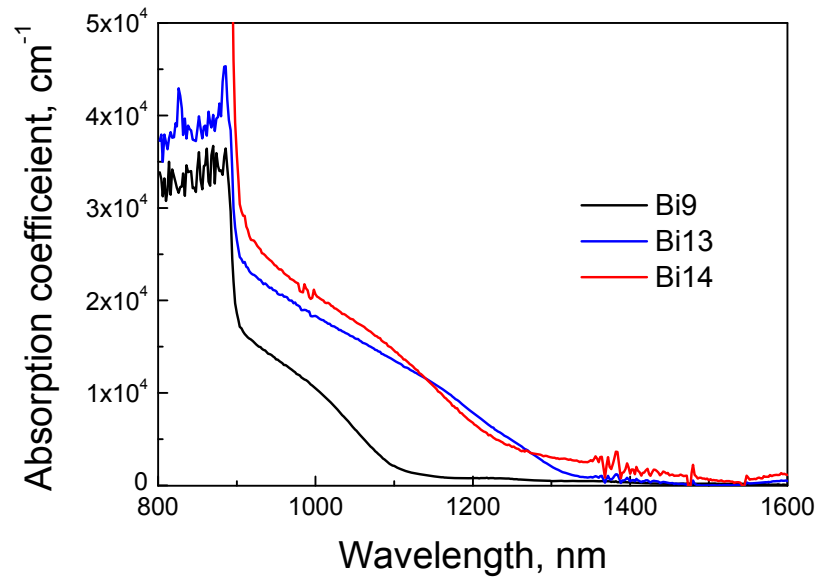
*W. Walukiewicz, Lawrence
Livermore Nat. Lab.*



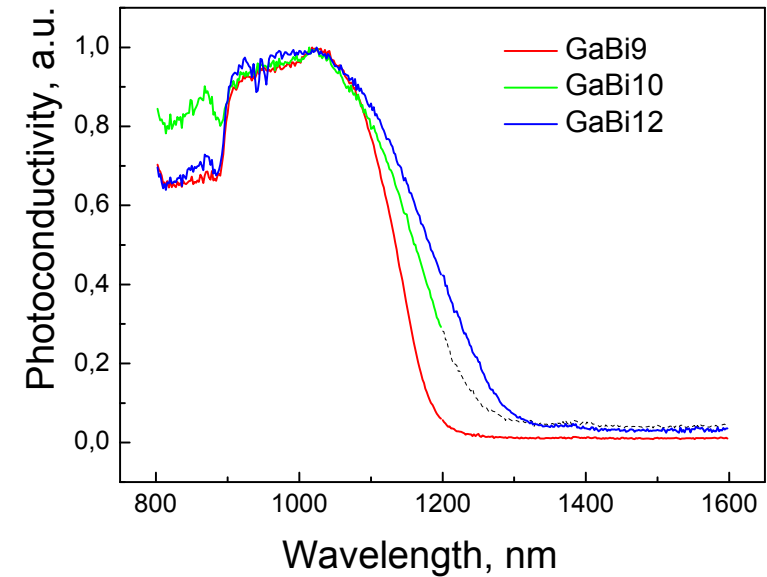
X-ray diffraction.



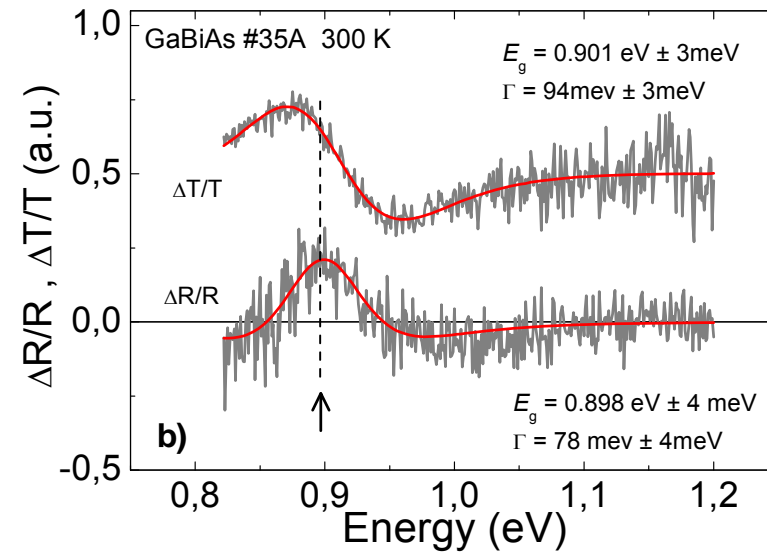
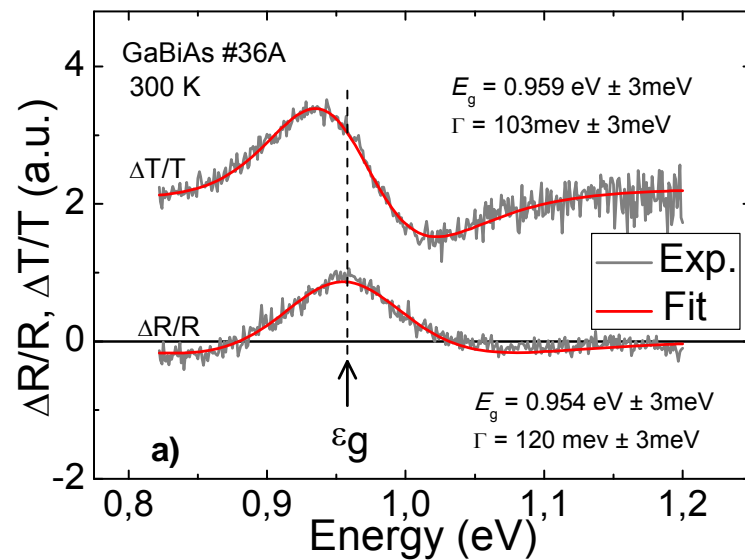
Energy bandgap



Optical absorption spectra at room temperature.



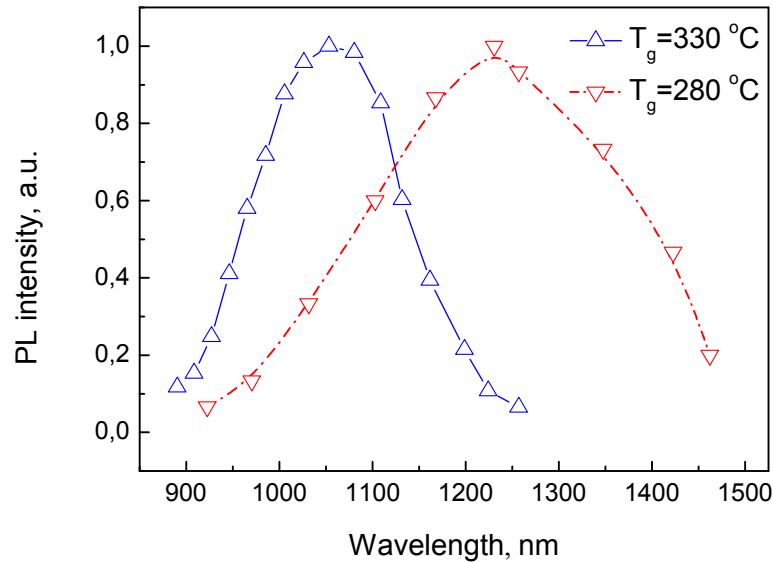
Photoconductivity spectra at room temperature.



Photomodulated transmittance ($\Delta T/T$) and photomodulated reflectance ($\Delta R/R$) spectra for two GaBiAs samples measured at room temperature.

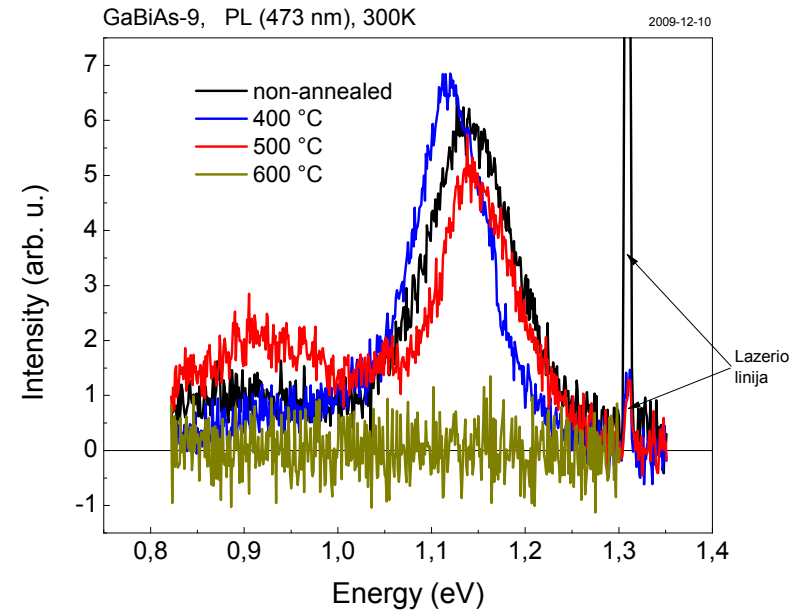


Photoluminescence



GaBiAs layers with the carrier lifetime shorter than 10 ps. PL measured by frequency up-conversion, single-photon counting technique.

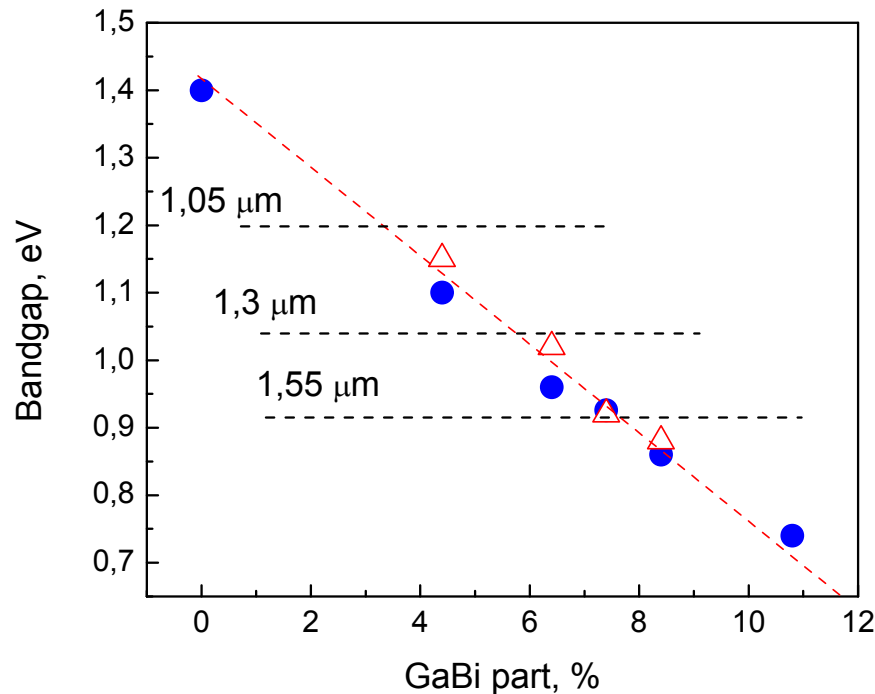
Prof. S. Marcinkevičius lab., KTH, Stockholm.



GaBiAs layer with a long carrier lifetime (~200 ps non-annealed). PL measured by a standard cw technique.

Complex annealing behavior.

Energy bandgap of GaBiAs



With the addition of Bi, the energy bandgap decreases at a rate of -62 meV/%Bi.

Other material parameters:

Conductivity – p-type.

Hole concentration $\sim 10^{15} \text{cm}^{-3}$,

*Hole mobility 20-200 cm^2/Vs
(decreasing in layers with a larger GaBi part).*

*Resistivity – typically 100's of $\Omega\cdot\text{cm}$
for nominally undoped layers; $>10^4$
 $\Omega\cdot\text{cm}$ in Si-compensated GaBiAs.*



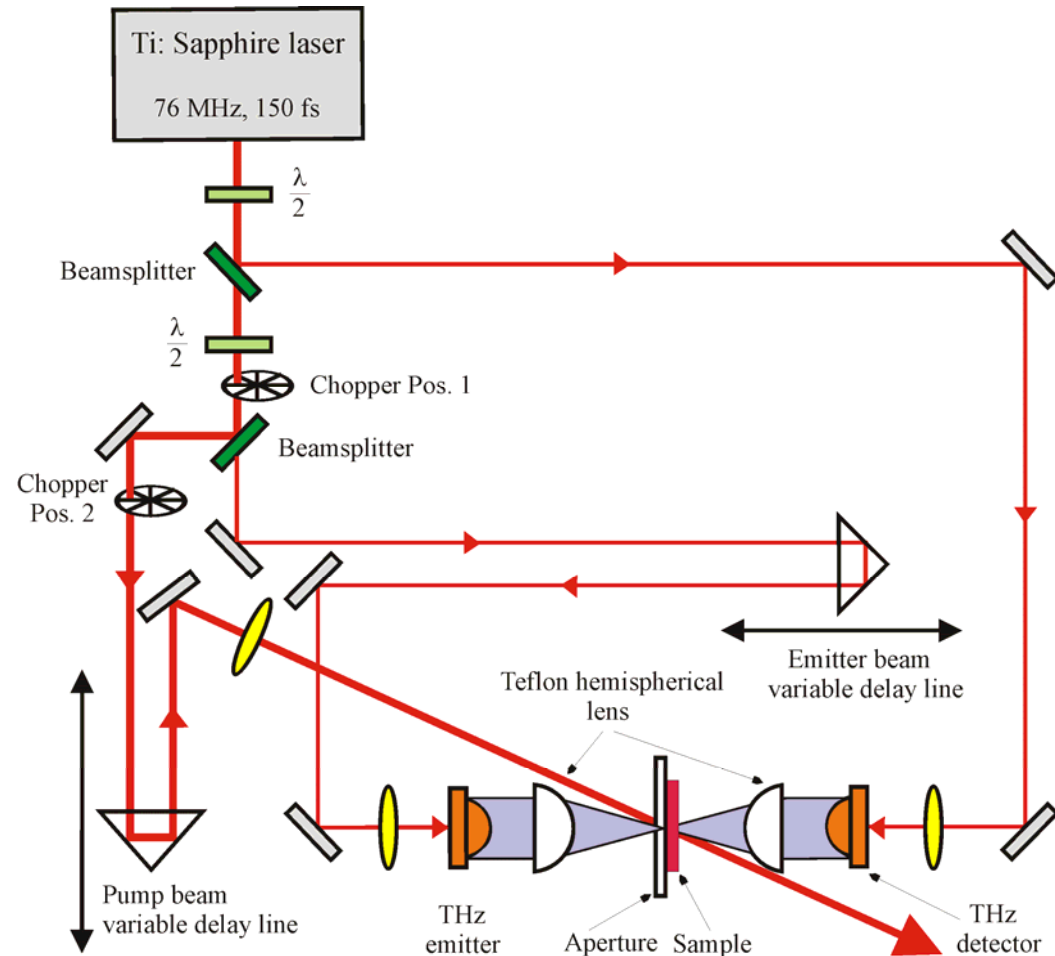
Lifetime measurement

Optical pump – THz probe experiment. THz pulse absorption caused by non-equilibrium electrons is measured at different time delays with respect to the sample photoexcitation.

Optically induced change in THz pulse transmittance is proportional to

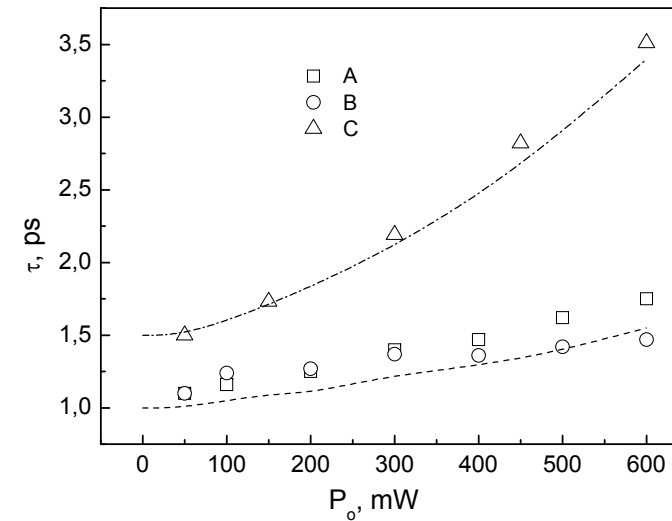
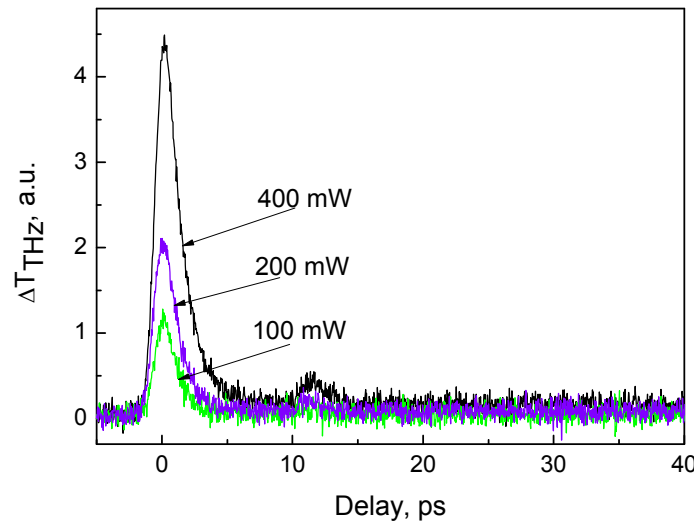
$$\ln(I/I_0) = -\alpha_i L = - (4\pi n_i / l_0) L \sim \sigma_{dc} \sim N\mu$$

Both the electron mobility and their lifetime can be determined.





Electron lifetime in GaBiAs



Lifetime varies from less than 1 ps to more than 200 ps. Electron mobility as determined from the amplitude of the induced THz absorption $>2000 \text{ cm}^2/\text{Vs}$.

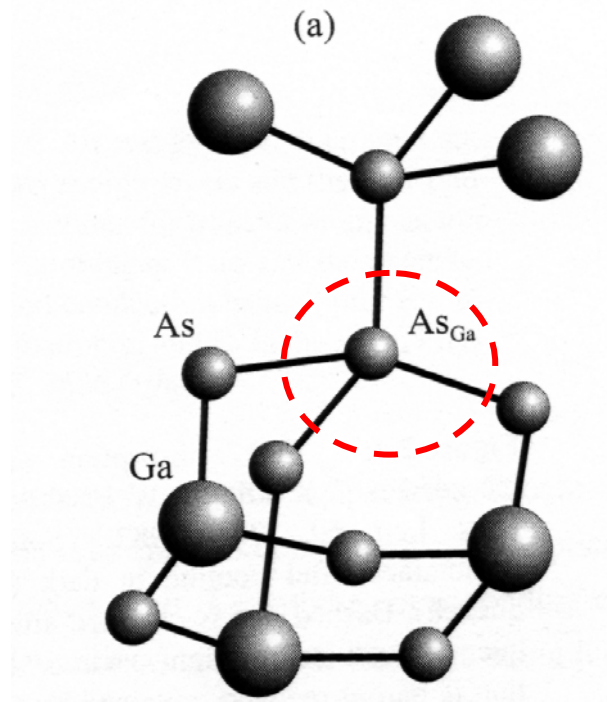
Electron lifetime is dependent on the photoexcitation level. Trap filling effect.

Best fit with a single trap model obtained for the capture cross-section of $4.5 \cdot 10^{-13} \text{ cm}^2$ and the trap density of $3 \cdot 10^{16} \text{ cm}^{-3}$ (sample A) and $4 \cdot 10^{16} \text{ cm}^{-3}$ (samples B and C).

V. Pačebutas et.al., pss(c), (2009)



Arsenic antisites



The main carrier trapping center in LTG GaAs.

Electron capture cross-section by As_{Ga} in GaAs– 10^{-13} cm^2

A. Krotkus et.al. IEE Proc. Optoelectron.,

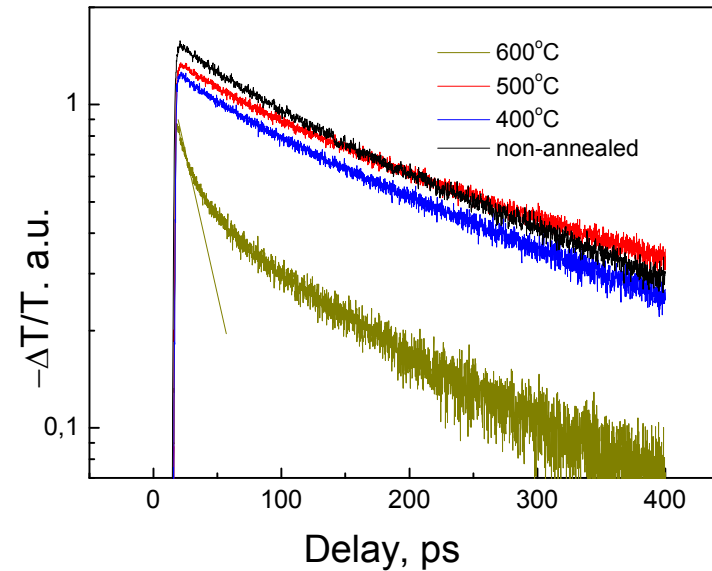
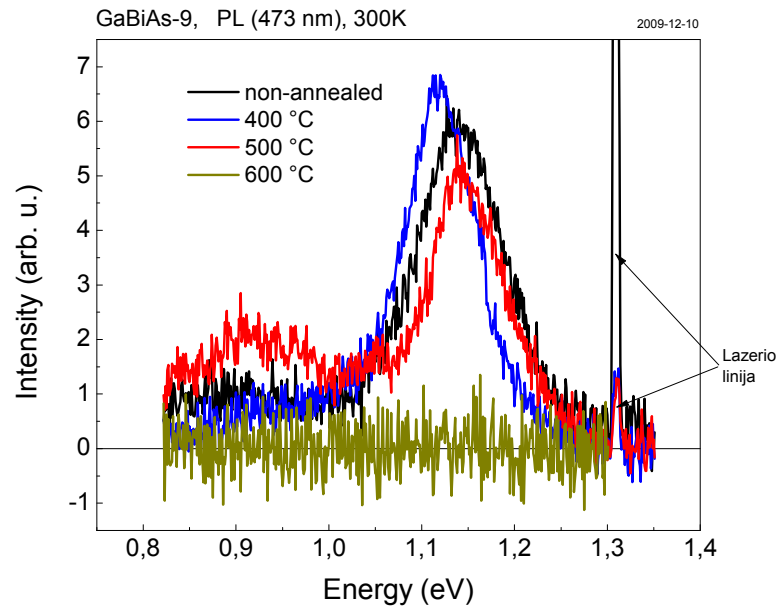
In LTG GaAs the lifetime increases after annealing because the majority of the excess As atoms precipitate into nm size clusters.

As-antisite. Point defect leading to a deep level in the band gap.

M.Kaminska, E.Weber, (1990)



Effect of the annealing



Photoluminescence in GaBiAs layer with a long carrier lifetime (~ 200 ps non-annealed). PL measured by a standard cw technique.

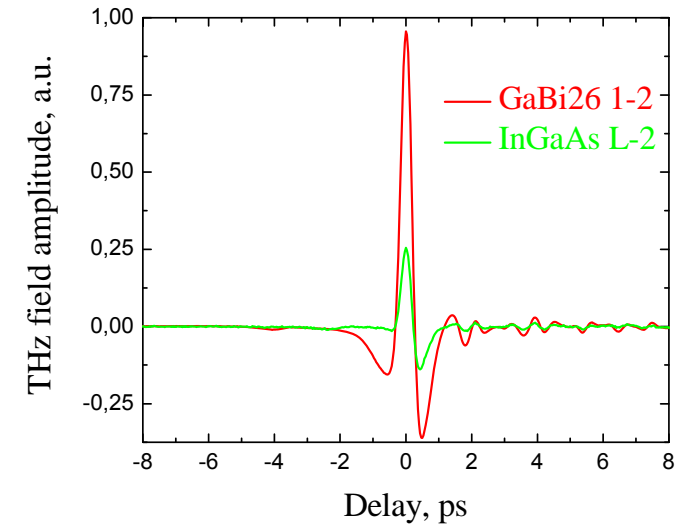
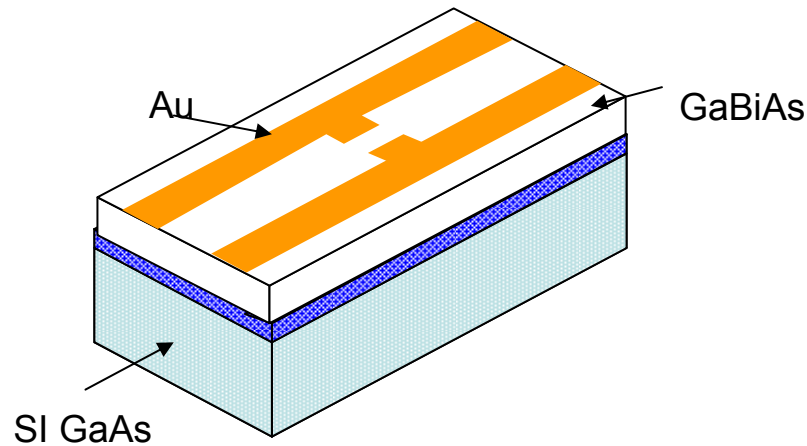
Complex annealing behavior. Additional PL band at $\sim 1.3 \mu\text{m}$ (Bi-clusters?)

THz probe measurement.

Lifetime in as-grown layer is ~ 200 ps, it slightly increases after anneal at 400 and 500°C, and drops to < 30 ps at $T=600^\circ\text{C}$.

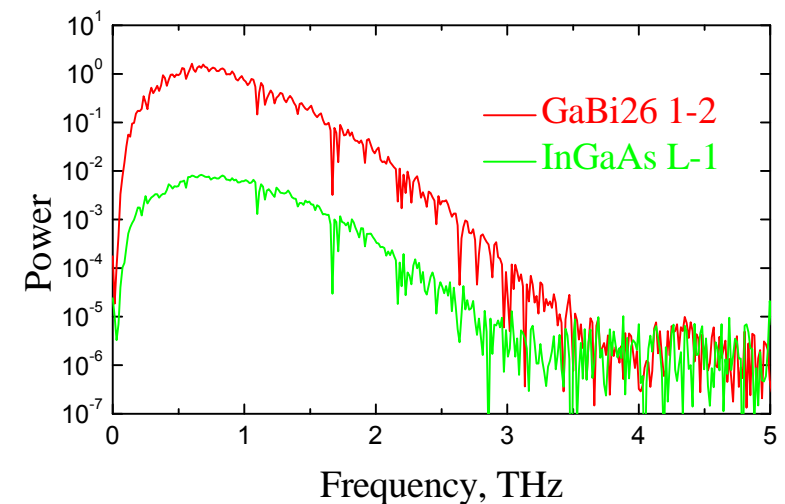


THz detectors



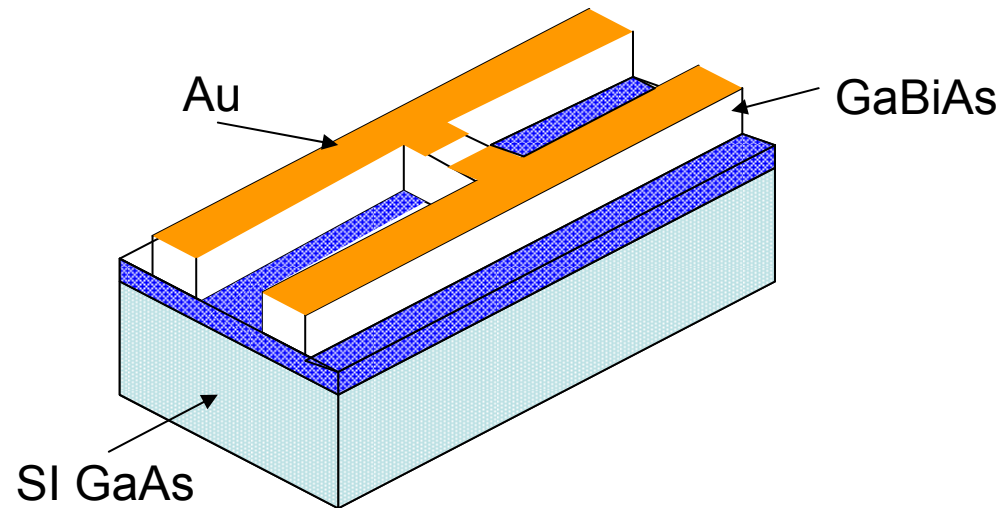
*The width of the gap – 15 μm .
Detected THz pulse amplitude is 5 times and
S/N ratio 100 times larger than when detector
made from LTG InGaAs layer is used.
THz emitter is p-type InAs.*

G. Molis et.al., Electron. Lett. 43,190-191 (2007)





THz emitters



The geometry of the antenna is similar to one used for THz detectors, except for mesa-etching of GaBiAs layer area between the microstriplines.

GaBiAs doping with Si used for residual p-type conduction compensation.

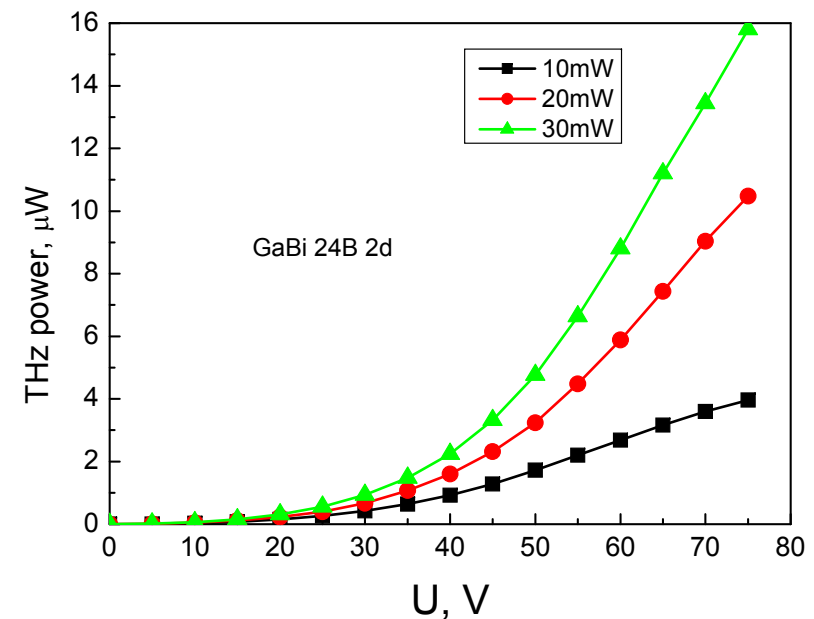
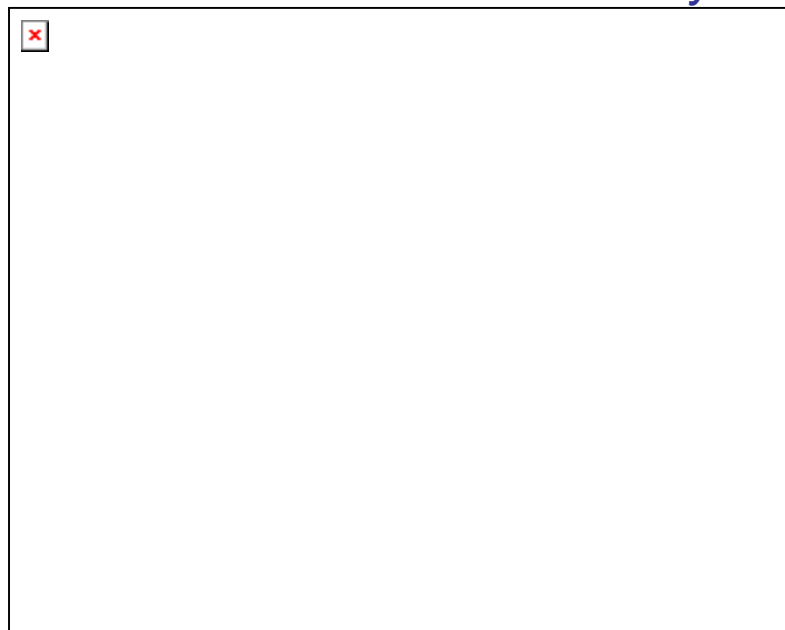
Dark resistance of the emitter $>100 M\Omega$. Breakdown field larger than 50 kV/cm.

Efficiency measurement

A **Golay Cell** is a type of detector mainly used for FIR spectroscopy. It consists of a small metal cylinder which is closed by a blackened metal plate at one end and by a flexible metalized diaphragm at the other. The cylinder is filled with Xe and then sealed.

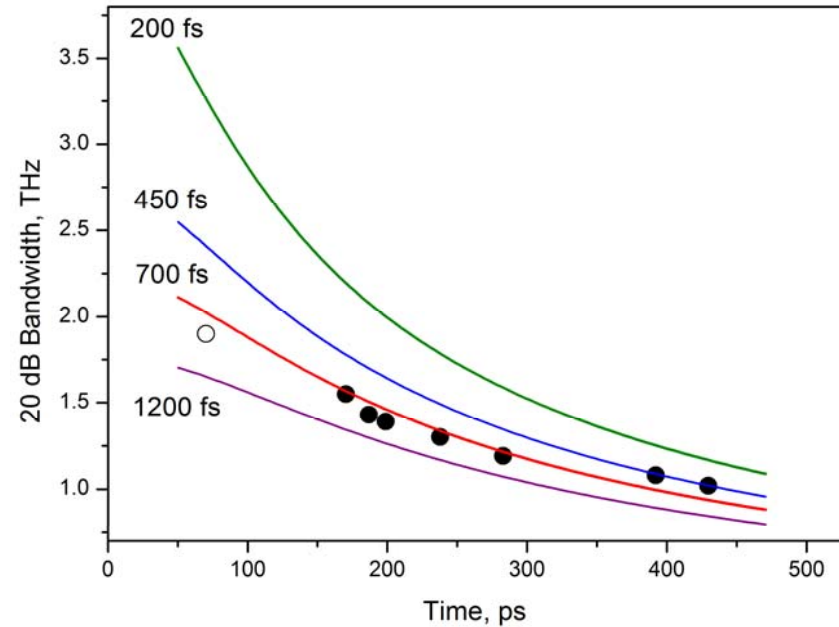
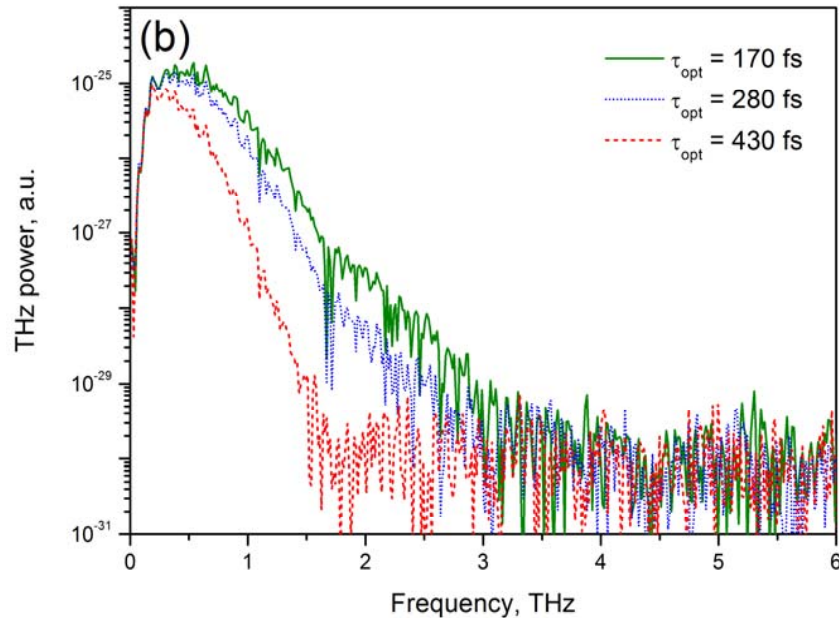
Measurements of THz power as functions of the bias voltage and the optical power.

Optical-to-THz conversion efficiency obtained was up to $7 \cdot 10^{-4}$, much better than $\sim 10^{-5}$ reached with other similar systems.



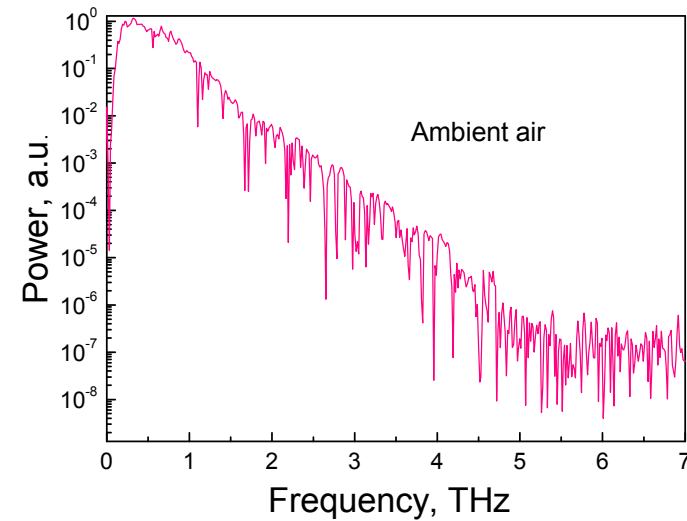
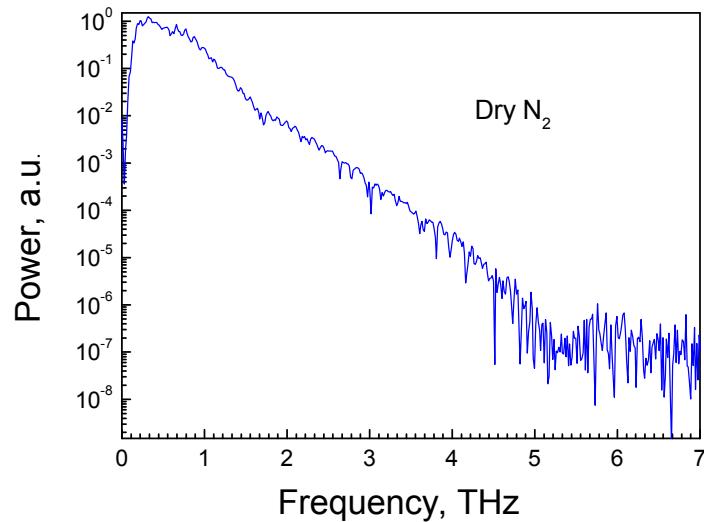


THz-TDS with a fiber laser



The Yb: fiber oscillator operated at a repetition rate of 45 MHz; an average output power of ~8 mW and ~11 mW was used for photoexcitation of the THz emitter and detector respectively.

20 dB-bandwidth of THz-TDS system as a function of the optical pulse duration. Solid lines – calculations for different carrier lifetimes in the detector.

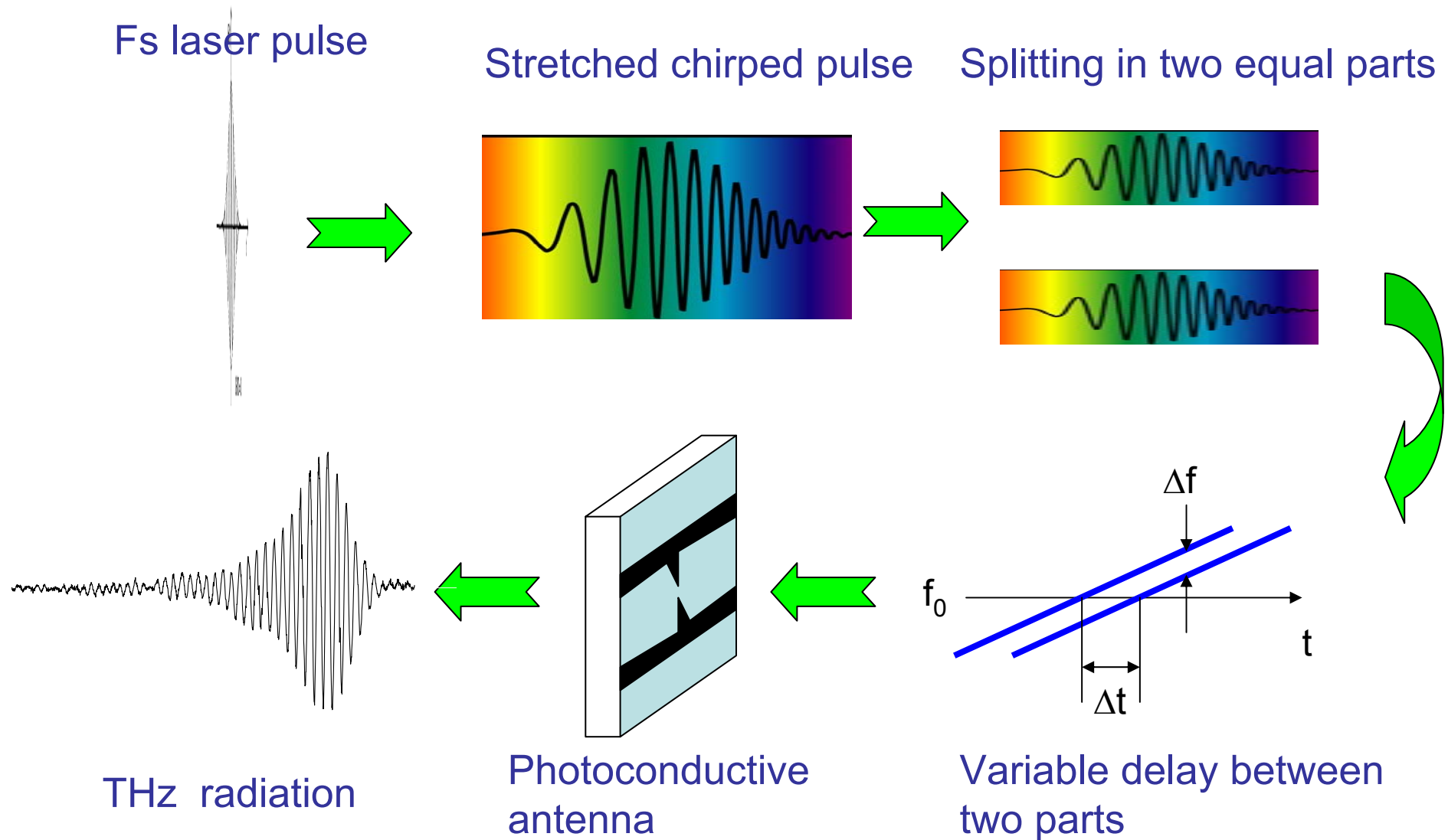


Yb:KGW laser, 1030 nm, 70 fs.

Spectral width ~5 THz, S/N ratio ~70 dB.

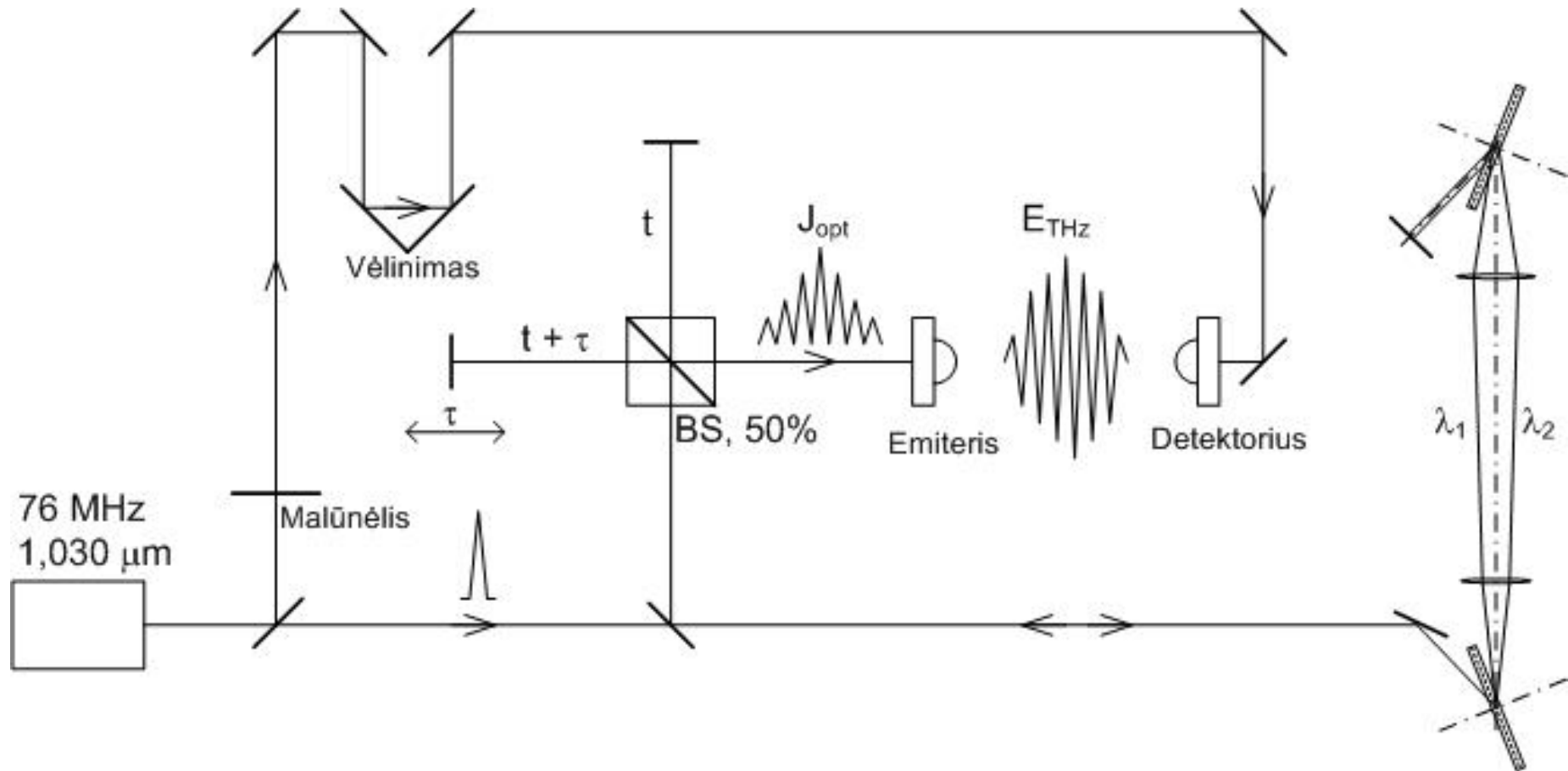
Average fs laser power of ~ 10 mW is sufficient for activating both the emitter and the detector.

THz burst generation



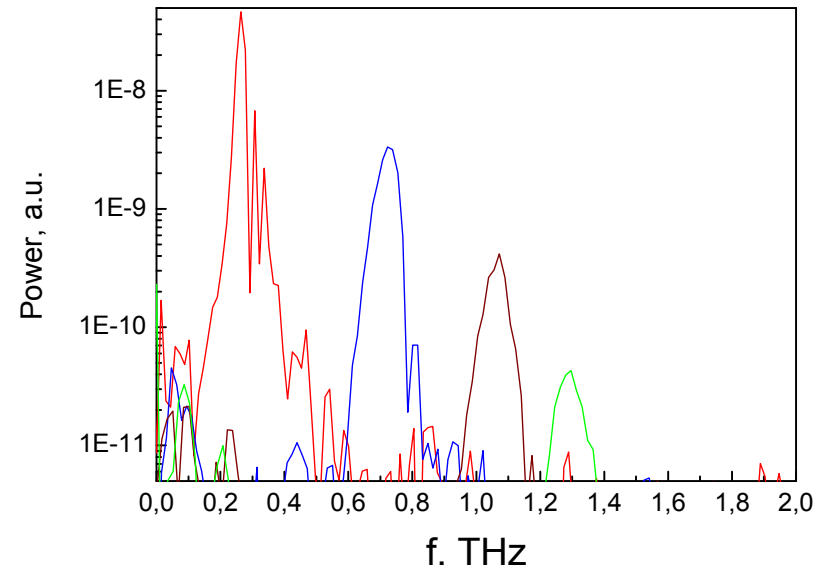
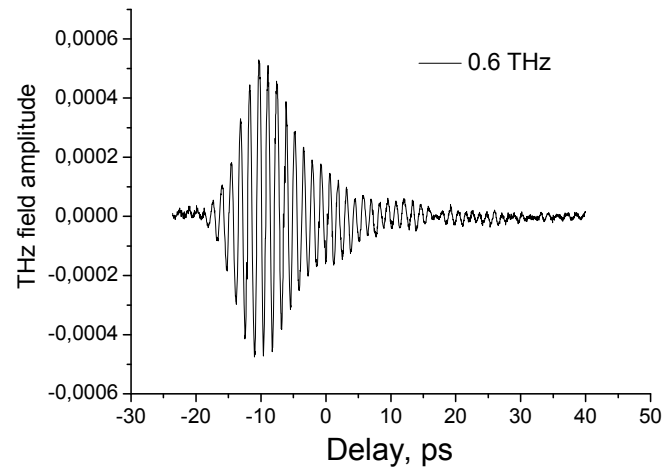
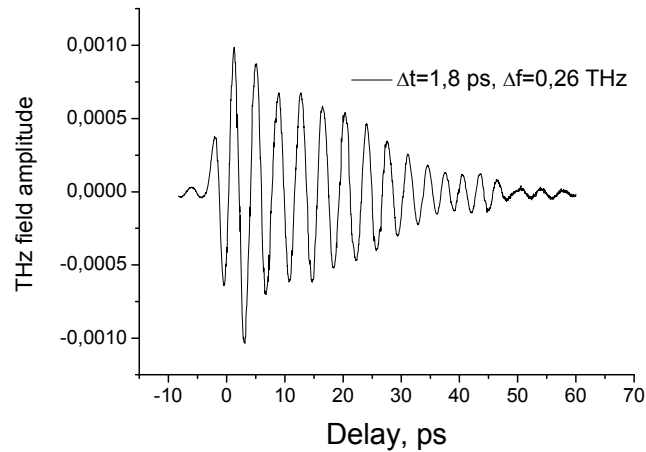


Experimental set-up





THz bursts from GaBiAs emitter



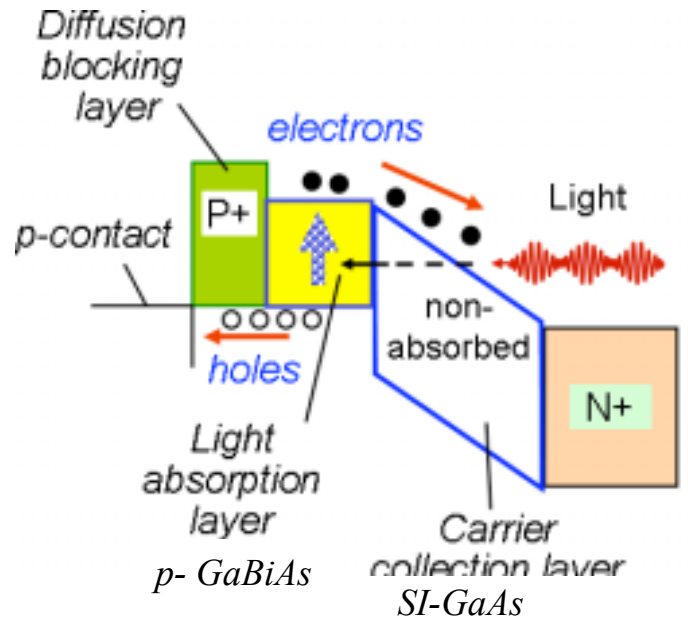
Emitter – Hertzian dipole, length $70\mu\text{m}$, resonance ~ 0.5 THz.

Yb:KGW laser pulses stretched to 30 ps, average optical power in both arms – 25 mW, bias voltage 30 V.

Maximum frequency observed 1.3 THz.

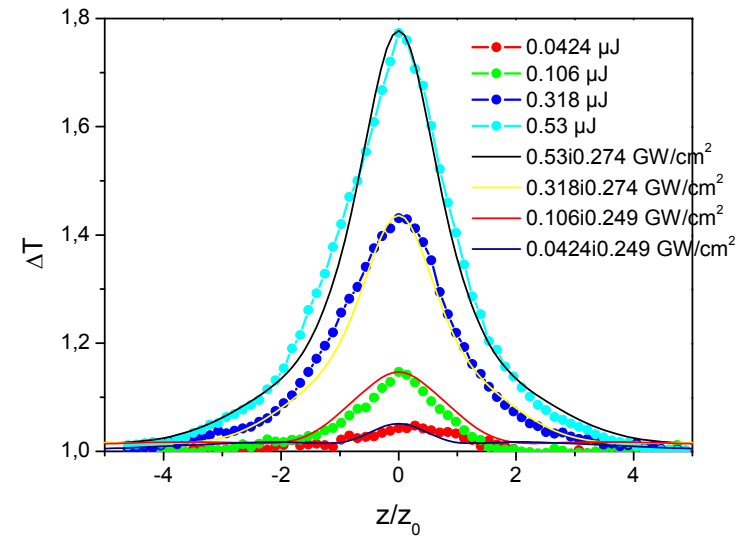


Other ultrafast applications



Uni-travelling carrier photodiode.

Response time limited by the electron sweep-out through the collection layer. Bandwidths >1 THz demonstrated.



Open aperture Z-scan measurement.

Large optical bleaching effect with relatively low saturation intensity.

Possible applications in saturable absorbers for mode-locked lasers and all-optical switches.



Conclusions

- ❖ Dilute GaBiAs due to its large electron mobility in a material with sub-picosecond carrier lifetimes is a prospective material for ultrafast optoelectronic application in the wavelength range of from 1 μm to 1.5 μm .
- ❖ THz time-domain-spectroscopy system with components manufactured from GaBiAs and activated by femtosecond pulses of compact 1-mm wavelength laser was demonstrated.
- ❖ This material shows great prospects in other ultrafast device applications, such as cw THz optical mixers, semiconducting saturable absorbers, and all-optical switches.